

Applicant: Eun-Taek Kim, et al.
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Title: METHOD FOR CLEANING A DEPOSITION CHAMBER AND DEPOSITION
APPARATUS FOR PERFORMING IN SITU CLEANING

INFORMATION DISCLOSURE CITATION
FORM PTO-1449 (Modified)

FOREIGN PATENT DOCUMENTS

<u>Exam</u> <u>Init</u>	<u>Ref</u>	<u>Document</u> <u>Number</u>	<u>Publication</u> <u>Date</u>	<u>Country</u>	<u>Name</u>
_____	_____	JP11222679	8/17/1999	Japan	Toshiyuki et al.

OTHER DOCUMENTS

<u>Exam</u> <u>Init</u>	<u>Ref</u>	<u>Author, Title, Date, Pertinent Pages, Etc.)</u>
_____	_____	English language Abstract from Japanese Patent Publication No. JP11222679 published 8/17/1999.

Examiner: _____

Date Considered: _____